

Receipt

533 Rec'd PCT/PTO 12 JUL 2002



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Reply, Application of

Docket No: Q60716

Hiromoto OHNO, et al.

Appln. No.: 10/088,306

Group Art Unit: 3749

Confirmation No.: 2926

Examiner: Not Yet Assigned

Filed: March 18, 2002

For: CLEANING GAS FOR SEMICONDUCTOR PRODUCTION EQUIPMENT

REQUEST FOR CORRECTED OFFICIAL FILING RECEIPT

Commissioner for Patents
Office of Initial Patent Examination
Customer Service Center
Washington, D.C. 20231

RECEIVED

JUL 24 2002

TECHNOLOGY CENTER R3700

Sir:

We enclose a copy of the Official Filing Receipt for the above-identified application and request the following correction(s):

Applicant(s)

Hiromoto Ohno, [Residence Not Provided] Kanagawa, JAPAN
Toshio Ohi, Kanagawa, JAPAN
Shuji Yoshida, Kanagawa, JAPAN
Manabu Ohhira, Kanagawa, JAPAN
Koutarou Tanaka, Kanagawa, JAPAN

Verification for the requested correction(s) is indicated on the original Declaration and Power of Attorney filed March 18, 2002.

Respectfully submitted,

Abraham J. Rosner
Registration No. 33,276

SUGHRUE MION, PLLC
2100 Pennsylvania Avenue, N.W.
Washington, D.C. 20037-3213
Telephone: (202) 293-7060
Facsimile: (202) 293-7860

Date: July 12, 2002

RECEIVED

JUL 25 2002

TECHNOLOGY CENTER R3700



UNITED STATES PATENT AND TRADEMARK OFFICE

JUL 12 2002

 COMMISSIONER FOR PATENTS
 UNITED STATES PATENT AND TRADEMARK OFFICE
 WASHINGTON, D.C. 20231
 www.uspto.gov

APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
10/088,308	06/11/2002	3749	1262	Q60716	1	36	4

CONFIRMATION NO. 2926

 23373
 SUGHRUE MION, PLLC
 2100 PENNSYLVANIA AVENUE, N.W.
 WASHINGTON, DC 20037

FILING RECEIPT



OC00000008249357

Date Mailed: 06/11/2002

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Kanagawa, JAPAN

Hiromoto Ohno, [Residence Not Provided]

Toshio Ohi, Kanagawa, JAPANShuji Yoshida, Kanagawa, JAPANManabu Ohhira, Kanagawa, JAPANKentarou Tanaka, Kanagawa, JAPAN

Domestic Priority data as claimed by applicant

THIS APPLICATION IS A 371 OF PCT/JP01/06164 07/17/2001 ✓
 WHICH CLAIMS BENEFIT OF 60/230,811 09/07/2000 * ✓
 AND CLAIMS BENEFIT OF 60/261,265 01/16/2001 * ✓
 (*)Data provided by applicant is not consistent with PTO records.

Foreign Applications

JAPAN 2000-217610 07/18/2000 ✓
 JAPAN 2000-397269 12/27/2000 ✓
 JAPAN 2001-189388 06/22/2001 ✓

Projected Publication Date: To Be Determined - pending completion of Security Review

Non-Publication Request: No

Early Publication Request: No

Title

Cleaning gas for semiconductor production equipment ✓

 RECEIVED
 JUL 25 2002
 TECHNOLOGY CENTER R3700

Preliminary Class
034

**LICENSE FOR FOREIGN FILING UNDER
Title 35, United States Code, Section 184
Title 37, Code of Federal Regulations, 5.11 & 5.15**

GRANTED

The applicant has been granted a license under 35 U.S.C. 184, if the phrase "IF REQUIRED, FOREIGN FILING LICENSE GRANTED" followed by a date appears on this form. Such licenses are issued in all applications where the conditions for issuance of a license have been met, regardless of whether or not a license may be required as set forth in 37 CFR 5.15. The scope and limitations of this license are set forth in 37 CFR 5.15(a) unless an earlier license has been issued under 37 CFR 5.15(b). The license is subject to revocation upon written notification. The date indicated is the effective date of the license, unless an earlier license of similar scope has been granted under 37 CFR 5.13 or 5.14.

This license is to be retained by the licensee and may be used at any time on or after the effective date thereof unless it is revoked. This license is automatically transferred to any related applications(s) filed under 37 CFR 1.53(d). This license is not retroactive.

The grant of a license does not in any way lessen the responsibility of a licensee for the security of the subject matter as imposed by any Government contract or the provisions of existing laws relating to espionage and the national security or the export of technical data. Licensees should apprise themselves of current regulations especially with respect to certain countries, of other agencies, particularly the Office of Defense Trade Controls, Department of State (with respect to Arms, Munitions and Implements of War (22 CFR 121-128)); the Office of Export Administration, Department of Commerce (15 CFR 370.10 (j)); the Office of Foreign Assets Control, Department of Treasury (31 CFR Parts 500+) and the Department of Energy.

NOT GRANTED

No license under 35 U.S.C. 184 has been granted at this time, if the phrase "IF REQUIRED, FOREIGN FILING LICENSE GRANTED" DOES NOT appear on this form. Applicant may still petition for a license under 37 CFR 5.12, if a license is desired before the expiration of 6 months from the filing date of the application. If 6 months has lapsed from the filing date of this application and the licensee has not received any indication of a secrecy order under 35 U.S.C. 181, the licensee may foreign file the application pursuant to 37 CFR 5.15(b).